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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>		Application Number	To be assigned
		Filing Date	
		First Named Inventor	John H.Jerman
		Group Art Unit	To be assigned
		Examiner Name	To be assigned
Sheet	1	of	2
		Attorney Docket Number	

1449A/PTO 06/91 U.S. P.T.O.

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Office ³	Number ⁴			
T	WO	98/09289	A1	Quinta Corporation	05/03/98	

**Examiner
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Date Considered

6/4/02

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 2 of 2

Complete if Known

Application Number	To be assigned
Filing Date	
First Named Inventor	John H. Jerman
Group Art Unit	To be assigned
Examiner Name	To be assigned
Attorney Docket Number	A-68185-1/ENB

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		L.S. Fan, et al.; "Batch-Fabricated Area-Efficient Milli-Actuators," Proceedings 1994 Solid State Sensor and Actuator Workshop, Hilton Head, pp 38-42	
		D.A. Horsley, et al.; "Angular Micropositioner for Disk Drives", Proceedings of the Tenth International Workshop on Micro Electro Mechanical Systems, 1997, pp 454-458;	
		T. Juneau, et al.; "Dual Axis Operation of a Micromachined Rate Gyroscope", Proceedings 1997 International Conference on Solid State Sensors and Actuators, V.2, pp 883-890	
		E.H. Klaassen, et al.; "Silicon Fusion Bonding and Deep Reactive Ion Etching; A New Technology for Microstructures", The 8 th International Conference on Solid-State Sensors and Actuators, and Eurosensors IX, Stockholm, Sweden, June 25-29, 1995, pp 556-559	
		J. Mohr, et al.; "Micro Optical Switching by Electrostatic Linear Actuators with Large Displacements", The 7 th International Conference on Solid-State Sensors and Actuators, pp 120-123	
		W.C. Tang, et al.; "Laterally Driven Polysilicon Resonant Microstructures", Sensors Actuators 20, 1989, pp 25-31 (IEEE reprint pp. 53-59)	

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